

Abstract

5 **Production process of a flat suspended micro-structure using a
sacrificial layer of polymer material and component obtained thereby**

10 The process successively comprises deposition of a sacrificial layer (2) of
polymer material, deposition, on at least a part of the substrate (1) and of the
front face of the sacrificial layer (2), of an embedding layer (6), the thickness
whereof is larger than that of the sacrificial layer (2), and planarization so that
the front faces of the sacrificial layer (2) and of the embedding layer (6) form a
common flat surface. A formation layer (3) of a suspended structure (5) is
deposited on the front face of the common flat surface. Planarization can
15 comprise chemical mechanical polishing and etching of the embedding layer
(6). Etching of the sacrificial layer (2) can be performed by means of a mask
formed on the front face of a layer of polymer material eliminated during the
planarization step.

20 (Figure 10)